

Abstract Of The Disclosure

A micromechanical component and a method of producing same are described; the component has a supporting body, in particular a silicon body, and a membrane which is connected to the supporting body and is unsupported at least in some areas. The membrane is also provided with at least one stabilizing element in an unsupported area in some areas of the surface. The method described here includes the following process steps: a) forming a first area within the supporting body including at least a first surface area of the supporting body ; b) forming a second surface area of the supporting body which is in the first surface area in at least some areas; c) selective etching of the first area down to an adjustable depth, forming porous silicon, the second surface area being at least almost not etched; d) depositing a membrane layer on the surface of the supporting body, with the membrane layer covering the first area that has been rendered porous in at least some areas and covering the second surface area in at least some areas, and e) selectively removing the first area which has been rendered porous.